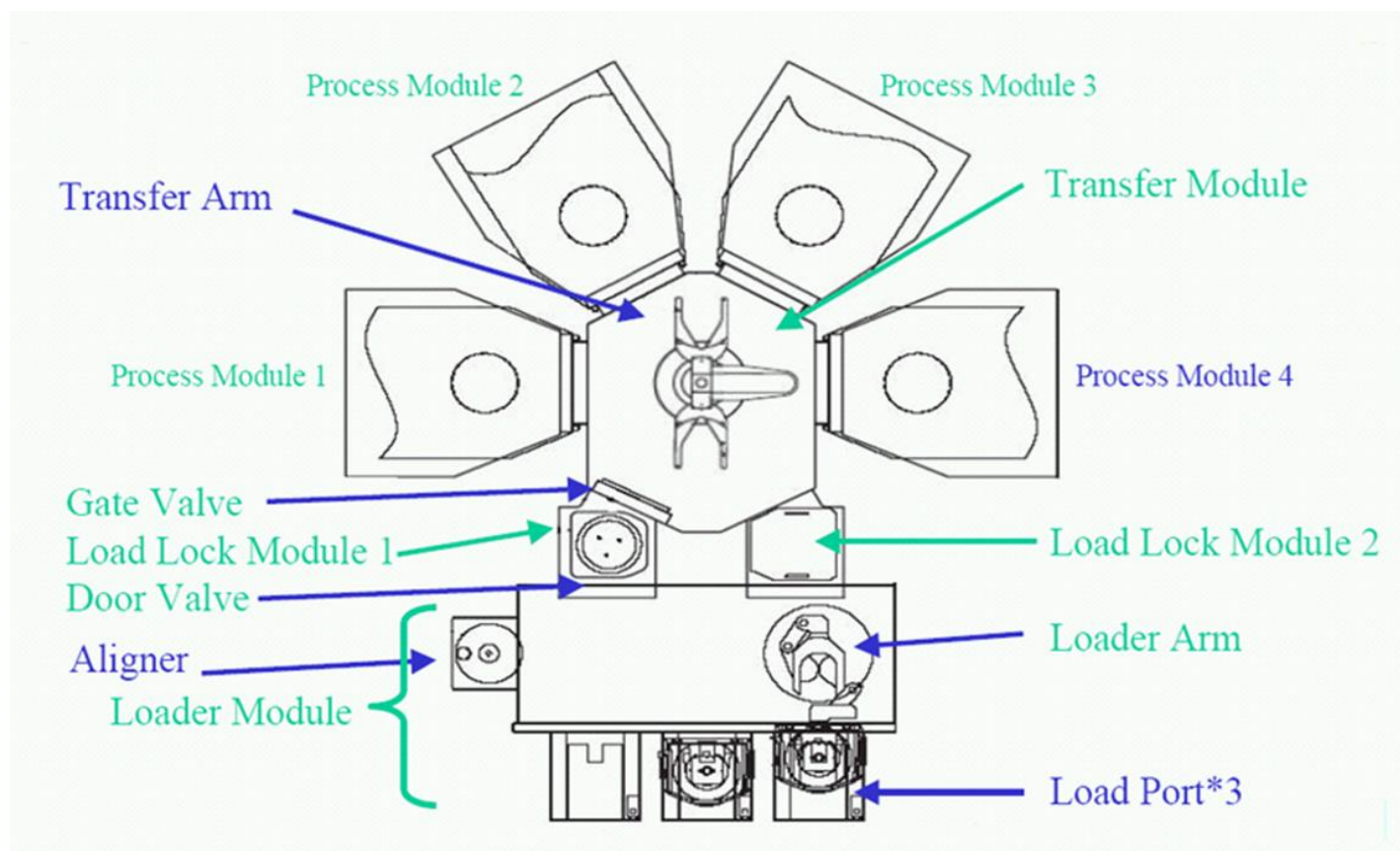


Process:	BL GL Ti Dep
Equipment ID:	TM-TB1-02
Model:	TEL Trias



S/N	Item	Maker	Model
	FI		
1	System		V1.91R1F4 PM1:V1.91R1 PM2:V1.91R1 PM3:V1.91R1 PM4:V1.91R1
2	Loadport configuration	Brooks	TLG-LON (3 Foup)
		SHINKO	SELOP12F25-30A-13
3	FI Robot	SHINKO	SBX92101286-3
	MainFrame		
4	Buffer robot	YASKAWA Electric Japan	XU-RVM4100
5	Loadloack configuration		Integrated 2-slot load blocks
6	LLM1.2 gate valve	V TEX	I-I-98009-2-1

7	Chamber gate valve	KITZ	DOUBLE ACTION
Process Chamber : PM1			
8	Single wafer chamber with stage heater		
9	Module heater controller	RKC instrument INC	
10	Module heater controller	TEL	TMC2001
11	MFC2 CIF3 500 sccm	SAM	SFC1470FA
12	MFC3 Ar 2 slm	SAM	SFC1480FA
13	MFC4 H2 5 slm	SAM	SFC1481FA
14	MFC5 NH3 0.6/2 slm	SAM	SFC1480FAPD
15	MFC7 N2 2 slm	SAM	SFC1480FA
16	MFM TiCl4 20 sccm	STEC	SEF-8240
17	Column trap		
18	RF gen	Kyosan	HFK15Z-TW1
19	RF Matcher	Kyosan	EAKIT
20	Regulator	Veriflo	SQ-MICRO-602PUPGPA
21	Pirani Sensor(P.SW11/12/21/32)	LEYBOLD	TSR211S
22	Pressure Sensor(PS.12/PS.31/PS.32)	PS.12/PS.32 LEYBOLD PS.31 INFICON	PS.12/PS.32 TSR211S PS.31 INFICON VSA100A
23	Capacitance Manometer(CM)	MKS	626A01TDE
24	Capacitance Manometer(1333Pa)	Leybold	CDG160A-S 1330PA
25	Capacitance Manometer(133KPa)	Leybold	CDG160A-S 133PA
26	Vapoizer(TiCl4)==>VC	STEC	VC131004ST20
Process Chamber : PM2			
27	Single wafer chamber with stage heater		
28	Module heater controller	RKC instrument INC	
29	Module heater controller	TEL	TMC2001
30	MFC2 CIF3 500 sccm	SAM	SFC1470FA
31	MFC3 Ar 2 slm	SAM	SFC1480FA
32	MFC4 H2 5 slm	SAM	SFC1481FA
33	MFC5 NH3 0.6/2 slm	SAM	SFC1480FAPD
34	MFC7 N2 2 slm	SAM	SFC1480FA
35	MFM TiCl4 20 sccm	STEC	SEF-8240
36	Column trap		
37	RF gen	Kyosan	HFK15Z-TW1
38	RF Matcher	Kyosan	EAKIT
39	Regulator	Veriflo	SQ-MICRO-602PUPGPA
40	Pirani Sensor(P.SW11/12/21/32)	LEYBOLD	TSR211S
41	Pressure Sensor(PS.12/PS.31/PS.32)	PS.12/PS.32 LEYBOLD PS.31 INFICON	PS.12/PS.32 TSR211S PS.31 INFICON VSA100A
42	Capacitance Manometer(CM)	MKS	626A01TDE
43	Capacitance Manometer(1333Pa)	Leybold	CDG160A-S 1330PA
44	Capacitance Manometer(133KPa)	Leybold	CDG160A-S 133PA
	Vapoizer(TiCl4)==>VC	STEC	VC131004ST20

Process Chamber : PM3			
45	Single wafer chamber with stage heater		
46	Module heater controller	RKC instrument INC	
47	Module heater controller	TEL	TMC2001
48	MFC2 CIF3 500 sccm	SAM	SFC1470FA
49	MFC3 Ar 2 slm	SAM	SFC1480FA
50	MFC4 H2 5 slm	SAM	SFC1481FA
51	MFC5 NH3 0.6/2 slm	SAM	SFC1480FAPD
52	MFC7 N2 2 slm	SAM	SFC1480FA
53	MFM TiCl4 20 sccm	STEC	SEF-8240
54	Column trap		
55	RF gen	Kyosan	HFK15Z-TW1
56	RF Matcher	Kyosan	EAKIT
57	Regulator	Veriflo	SQ-MICRO-602PUPGPA
58	Pirani Sensor(P.SW11/12/21/32)	LEYBOLD	TSR211S
59	Pressure Sensor(PS.12/PS.31/PS.32)	PS.12/PS.32 LEYBOLD PS.31 INFICON	PS.12/PS.32 TSR211S PS.31 INFICON VSA100A
60	Capacitance Manometer(CM)	MKS	626A01TDE
61	Capacitance Manometer(1333Pa)	Leybold	CDG160A-S 1330PA
62	Capacitance Manometer(133KPa)	Leybold	CDG160A-S 133PA
	Vapoizer(TiCl4)=>VC	STEC	VC131004ST20
Process Chamber : PM4			
63	Single wafer chamber with stage heater		
64	Module heater controller	RKC instrument INC	
65	Module heater controller	TEL	TMC2001
66	MFC2 CIF3 500 sccm	SAM	SFC1470FA
67	MFC3 Ar 2 slm	SAM	SFC1480FA
68	MFC4 H2 5 slm	SAM	SFC1481FA
69	MFC5 NH3 0.6/2 slm	SAM	SFC1480FAPD
70	MFC7 N2 2 slm	SAM	SFC1480FA
71	MFM TiCl4 20 sccm	STEC	SEF-8240
72	Column trap		
73	RF gen	Kyosan	HFK15Z-TW1
74	RF Matcher	Kyosan	EAKIT
75	Regulator	Veriflo	SQ-MICRO-602PUPGPA
76	Pirani Sensor(P.SW11/12/21/32)	LEYBOLD	TSR211S
77	Pressure Sensor(PS.12/PS.31/PS.32)	PS.12/PS.32 LEYBOLD PS.31 INFICON	PS.12/PS.32 TSR211S PS.31 INFICON VSA100A
78	Capacitance Manometer(CM)	MKS	626A01TDE
79	Capacitance Manometer(1333Pa)	Leybold	CDG160A-S 1330PA
80	Capacitance Manometer(133KPa)	Leybold	CDG160A-S 133PA
	Vapoizer(TiCl4)=>VC	STEC	VC131004ST20

Subfab			
81	UPS	Fuji Electric Systems	M-UPS050J22L-UL
82	Chiller	三榮技研株式會社	TL7KCPVB-2P
83	MPD	TEL	
84	Transformer Box	TEL	Trias TB_TR2_T2

